Fully Automatic Reflectivity Mapping System

Make: ETAMAX

Model : UniMAP

General Description:

1. Main Frame
- X-Y stage : AC servo control
- Cassette Holder : Six with flexibility for 2",4",6"
- Operating Cassette Size : 2", 4", 6"

- Auto Loader : Robot Type
- Flat Zone Finder
- Z-Stage Adjustment
2. Light source
- White LED : Reflectance Measurement
- LED intensity Monitroring : One Sensor
3. Spectrometer
- 3636 pixels in total
- Wavelength Range : 420 nm span : 380-800nm
- Hardward pixel resolution : 0.13nm / pixel
- Optic Slit : 50 um
- USB Control.
4. Optics : One set including Filters and Lens.
5. Measurements
- Wafer surface uniformity / Reflectance : by Spectometer
- Wafer surface uniformity calculated by max-min/max+min
- Wafer surface uniformity calculated by standard deviation
- Max value and min value of reflectance
6. Data Acquisition PC : One set, Window 7 with 17" LCD monitor
7. Measurement data connects with MIS system shared to users
8. Data Acquisition S/W : One set
- Uniformity / Reflectance Mapping for PSS
- Data access is possible by LAN
9. Sorting Funtion
- Recipe setting by customers based on average reading or standard deviation
- Recipe setting by customers based on man, min value and uniformiy calculated by max-min/max+min
- Mapping of datas measured on all the wafer surface
10. Facility requirements (provided by Customer)
- Foot Print : 144 x 88 x 150(cm) (W-D-H)
- Weight : ~ 470Kg
- Power : 220V / 30A, 3 wires.
- CDA : 0.2 ~ 0.4 Mpa

System will come with 12ea 2" cassettes, 6ea 4" cassettes, 6ea 6" cassettes